L Number	Hits	Search Text	DB	Time stamp
7	14031	(photoresist or photosensitive) and	USPAT;	2004/10/29 09:05
		(mask\$4 or print\$4 or record\$4) and	US-PGPUB;	
		((circul\$6 or rotat\$5) same (stage\$1 or	EPO; JPO;	
		table\$1 or subtrate\$1 or wafer\$1 or	DERWENT	
	2525	objet\$1))	.,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,	0004/10/00 00 11
8	2507	, · · · · · · · · · · · · · · · · · · ·	USPAT;	2004/10/29 08:41
		(mask\$4 or print\$4 or record\$4) and	US-PGPUB;	
		((circul\$6 or rotat\$5) same (stage\$1 or table\$1 or subtrate\$1 or wafer\$1 or	EPO; JPO; DERWENT	
		objet\$1))) and ((jet\$4 or eject\$4 or	DEKWENI	
		discharg\$4) same (mask\$4 or print\$4 or		
		record\$4)) and ((circul\$6 or rotat\$5)		
		same (stage\$1 or table\$1 or subtrate\$1 or		
		wafer\$1 or objet\$1))		
9	948	(((photoresist or photosensitive) and	USPAT;	2004/10/29 08:41
_		(mask\$4 or print\$4 or record\$4) and	US-PGPUB;	
		((circul\$6 or rotat\$5) same (stage\$1 or	EPO; JPO;	
		table\$1 or subtrate\$1 or wafer\$1 or	DERWENT	
		objet\$1))) and ((jet\$4 or eject\$4 or		
		discharg\$4) same (mask\$4 or print\$4 or		
		record\$4)) and ((circul\$6 or rotat\$5)		
		same (stage\$1 or table\$1 or subtrate\$1 or		
		wafer\$1 or objet\$1))) and ((jet\$4 or		
		eject\$4 or discharg\$4) same (mask\$4 or		
		print\$4 or record\$4) same (photosensitive		
10	503	or photoresist)) ((((photoresist or photosensitive) and	USPAT;	2004/10/29 08:41
10	503	((((photoresist or photosensitive) and (mask\$4 or print\$4 or record\$4) and	US-PGPUB;	2004/10/29 00:41
		((circul\$6 or rotat\$5) same (stage\$1 or	EPO; JPO;	
		table\$1 or subtrate\$1 or wafer\$1 or	DERWENT	
		objet\$1))) and ((jet\$4 or eject\$4 or		
		discharg\$4) same (mask\$4 or print\$4 or		
		record\$4)) and ((circul\$6 or rotat\$5)		
		same (stage\$1 or table\$1 or subtrate\$1 or		
		wafer\$1 or objet\$1))) and ((jet\$4 or		
[eject\$4 or discharg\$4) same (mask\$4 or		1
		print\$4 or record\$4) same (photosensitive		
		or photoresist))) and ((circul\$6 or		
		rotat\$5) with (stage\$1 or table\$1 or		
11	77	subtrate\$1 or wafer\$1 or objet\$1))	USPAT;	2004/10/29 08:42
11	''	(((((photoresist or photosensitive) and (mask\$4 or print\$4 or record\$4) and	USPAT; US-PGPUB;	2004/10/23 00:42
		((circul\$6 or rotat\$5) same (stage\$1 or	EPO; JPO;	
		table\$1 or subtrate\$1 or wafer\$1 or	DERWENT	
		objet\$1))) and ((jet\$4 or eject\$4 or		
		discharg\$4) same (mask\$4 or print\$4 or		
		record\$4)) and ((circul\$6 or rotat\$5)		
		same (stage\$1 or table\$1 or subtrate\$1 or		
		wafer\$1 or objet\$1))) and ((jet\$4 or		
		eject\$4 or discharg\$4) same (mask\$4 or		
		print\$4 or record\$4) same (photosensitive		
		or photoresist))) and ((circul\$6 or		
		rotat\$5) with (stage\$1 or table\$1 or		
		subtrate\$1 or wafer\$1 or objet\$1))) and 347/\$.ccls.		
13	40		USPAT;	2004/10/29 08:44
12	48	((((((photoresist or photosensitive) and (mask\$4 or print\$4 or record\$4) and	US-PGPUB;	2004/10/29 00.44
		((circul\$6 or rotat\$5) same (stage\$1 or	EPO; JPO;	
		table\$1 or subtrate\$1 or wafer\$1 or	DERWENT	
		objet\$1))) and ((jet\$4 or eject\$4 or		
		discharg\$4) same (mask\$4 or print\$4 or	Į	
		record\$4)) and ((circul\$6 or rotat\$5)	1	
ļ		same (stage\$1 or table\$1 or subtrate\$1 or		
		wafer\$1 or objet\$1))) and ((jet\$4 or		
		eject\$4 or discharg\$4) same (mask\$4 or		
		print\$4 or record\$4) same (photosensitive		
		or photoresist))) and ((circul\$6 or		
		rotat\$5) with (stage\$1 or table\$1 or		
		subtrate\$1 or wafer\$1 or objet\$1))) and		
		347/\$.ccls.) and align\$4	L	

14	1 25	[[[[]]]]]] [[]] [] [] []	IICDAM.	2004/10/20 00-44
14	35	(((((((photoresist or photosensitive) and	USPAT; US-PGPUB;	2004/10/29 08:44
		<pre>(mask\$4 or print\$4 or record\$4) and ((circul\$6 or rotat\$5) same (stage\$1 or</pre>	EPO; JPO;	
		table\$1 or subtrate\$1 or wafer\$1 or	DERWENT	
			DERWEIT	
		objet\$1))) and ((jet\$4 or eject\$4 or discharg\$4) same (mask\$4 or print\$4 or		
		record\$4)) and ((circul\$6 or rotat\$5)		
		same (stage\$1 or table\$1 or subtrate\$1 or		
		wafer\$1 or objet\$1))) and ((jet\$4 or		
		eject\$4 or discharg\$4) same (mask\$4 or		
		print\$4 or record\$4) same (photosensitive		
		or photoresist))) and ((circul\$6 or		
	1	rotat\$5) with (stage\$1 or table\$1 or		
		subtrate\$1 or wafer\$1 or objet\$1))) and		
		347/\$.ccls.) and align\$4) and pattern\$1		
15	18	(((((((photoresist or photosensitive) and	USPAT;	2004/10/29 08:48
		(mask\$4 or print\$4 or record\$4) and	US-PGPUB;	
		((circul\$6 or rotat\$5) same (stage\$1 or	EPO; JPO;	
		table\$1 or subtrate\$1 or wafer\$1 or	DERWENT	
	1	objet\$1))) and ((jet\$4 or eject\$4 or		
		discharg\$4) same (mask\$4 or print\$4 or		
		record\$4)) and ((circul\$6 or rotat\$5)		
		same (stage\$1 or table\$1 or subtrate\$1 or		
		wafer\$1 or objet\$1))) and ((jet\$4 or	•	
		eject\$4 or discharg\$4) same (mask\$4 or		
		print\$4 or record\$4) same (photosensitive		
		or photoresist))) and ((circul\$6 or		
l		rotat\$5) with (stage\$1 or table\$1 or		
		subtrate\$1 or wafer\$1 or objet\$1))) and		
1		347/\$.ccls.) and align\$4) and pattern\$1)		
		and (mask\$4 with pattern\$1)	1	
16	17	((((((((photoresist or photosensitive) and	USPAT;	2004/10/29 08:50
		(mask\$4 or print\$4 or record\$4) and	US-PGPUB;	
		((circul\$6 or rotat\$5) same (stage\$1 or	EPO; JPO;	
		table\$1 or subtrate\$1 or wafer\$1 or	DERWENT	
		objet\$1))) and ((jet\$4 or eject\$4 or		
		discharg\$4) same (mask\$4 or print\$4 or		1
		record\$4)) and ((circul\$6 or rotat\$5) same (stage\$1 or table\$1 or subtrate\$1 or		
		wafer\$1 or objet\$1))) and ((jet\$4 or		
		eject\$4 or discharg\$4) same (mask\$4 or		
		print\$4 or record\$4) same (photosensitive		
		or photoresist))) and ((circul\$6 or		
		rotat\$5) with (stage\$1 or table\$1 or		
		subtrate\$1 or wafer\$1 or objet\$1))) and		
		347/\$.ccls.) and align\$4) and pattern\$1)		
		not ((((((((photoresist or		
		photosensitive) and (mask\$4 or print\$4 or		
		record\$4) and ((circul\$6 or rotat\$5) same		
		(stage\$1 or table\$1 or subtrate\$1 or		
		wafer\$1 or objet\$1))) and ((jet\$4 or		1
		eject\$4 or discharg\$4) same (mask\$4 or		
		print\$4 or record\$4)) and ((circul\$6 or		
		rotat\$5) same (stage\$1 or table\$1 or		
		subtrate\$1 or wafer\$1 or objet\$1))) and		
		((jet\$4 or eject\$4 or discharg\$4) same		
		(mask\$4 or print\$4 or record\$4) same		
		(photosensitive or photoresist))) and		
		((circul\$6 or rotat\$5) with (stage\$1 or table\$1 or subtrate\$1 or wafer\$1 or		
		objet\$1))) and 347/\$.ccls.) and align\$4)		
		and pattern\$1) and (mask\$4 with		
		pattern\$1))		
L		Nacceruatii	<u> </u>	<u> </u>

19 426	((((((photoresist or photosensitive) and (mask\$4 or print\$4 or record\$4) and ((circul\$6 or rotat\$5) same (stage\$1 or table\$1 or subtrate\$1 or wafer\$1 or objet\$1)) and ((jet\$4 or eject\$4 or discharg\$4) same (mask\$4 or print\$4 or record\$4) and ((circul\$6 or rotat\$5) same (stage\$1 or table\$1 or subtrate\$1 or wafer\$1 or objet\$1)) and ((jet\$4 or eject\$4 or discharg\$4) same (mask\$4 or print\$4 or record\$4) same (mask\$4 or print\$4 or rotat\$5) with (stage\$1 or table\$1 or subtrate\$1 or wafer\$1 or objet\$1)) and 347/\$.ccls.) not ((((((()(photoresist or photosensitive) and (mask\$4 or print\$4 or record\$4) and ((circul\$6 or rotat\$5) same (stage\$1 or table\$1 or subtrate\$1 or wafer\$1 or objet\$1)) and ((jet\$4 or eject\$4 or discharg\$4) same (mask\$4 or print\$4 or record\$4) and ((circul\$6 or rotat\$5) same (stage\$1 or table\$1 or subtrate\$1 or wafer\$1 or objet\$1))) and ((jet\$4 or eject\$4 or discharg\$4) same (mask\$4 or print\$4 or record\$4) same (mask\$4 or print\$4 or record\$4) same (mask\$4 or print\$4 or record\$4) same (foicicul\$6 or rotat\$5) with (stage\$1 or table\$1 or subtrate\$1 or wafer\$1 or objet\$1))) and (((i((photoresist or photosensitive) and (mask\$4 or print\$4 or record\$4) and ((circul\$6 or rotat\$5) same (stage\$1 or table\$1 or subtrate\$1 or wafer\$1 or objet\$1))) and ((jet\$4 or eject\$4 or discharg\$4) same (mask\$4 or print\$4 or record\$4) and ((circul\$6 or rotat\$5) same (stage\$1 or table\$1 or subtrate\$1 or wafer\$1 or objet\$1))) and ((jet\$4 or eject\$4 or discharg\$4) same (mask\$4 or print\$4 or record\$4) same (stage\$1 or table\$1 or subtrate\$1 or subtrate\$1 or subtrate\$1 or subtrate\$1 or objet\$1))) and ((jet\$4 or eject\$4 or discharg\$4) same (mask\$4 or print\$4 or record\$4) and ((circul\$6 or rotat\$5) same (stage\$1 or table\$1 or subtrate\$1 or wafer\$1 or objet\$1))) and ((jet\$4 or eject	USPAT; US-PGPUB; EPO; JPO; DERWENT; US-PGPUB; EPO; JPO; DERWENT	2004/10/29 09:03
	or photoresist))) and ((circul\$6 or		
	rotat\$5) with (stage\$1 or table\$1 or		
	subtrate\$1 or wafer\$1 or objet\$1))) and 347/\$.ccls.)		

20	115	((((((photoresist or photosensitive) and	USPAT;	2004/10/29 09:11
20	113	(mask\$4 or print\$4 or record\$4) and	US-PGPUB;	2004/10/25 05:11
	Į.	((circul\$6 or rotat\$5) same (stage\$1 or	EPO; JPO;	
		table\$1 or subtrate\$1 or wafer\$1 or	DERWENT	
		objet\$1))) and ((jet\$4 or eject\$4 or	221112111	
		discharg\$4) same (mask\$4 or print\$4 or		
		record\$4)) and ((circul\$6 or rotat\$5)		
1		same (stage\$1 or table\$1 or subtrate\$1 or		
		wafer\$1 or objet\$1))) and ((jet\$4 or		
		eject\$4 or discharg\$4) same (mask\$4 or		
		print\$4 or record\$4) same (photosensitive		
		or photoresist))) and ((circul\$6 or		
		rotat\$5) with (stage\$1 or table\$1 or		
		subtrate\$1 or wafer\$1 or objet\$1))) not		
		((((((photoresist or photosensitive) and		
		(mask\$4 or print\$4 or record\$4) and		
		((circul\$6 or rotat\$5) same (stage\$1 or		
		table\$1 or subtrate\$1 or wafer\$1 or		
		objet\$1))) and ((jet\$4 or eject\$4 or		
		discharg\$4) same (mask\$4 or print\$4 or		
		record\$4)) and ((circul\$6 or rotat\$5)		
		same (stage\$1 or table\$1 or subtrate\$1 or		
		wafer\$1 or objet\$1))) and ((jet\$4 or		
	ļ	eject\$4 or discharg\$4) same (mask\$4 or		
		print\$4 or record\$4) same (photosensitive		
		or photoresist))) and ((circul\$6 or		
		rotat\$5) with (stage\$1 or table\$1 or		
		subtrate\$1 or wafer\$1 or objet\$1))) and		
		347/\$.ccls.)) and ((photoresist or		
		photosensitive) add layer\$1)		
1	1	hincozenziciae) adl raleisi)	I	1

21 311	1 1 1 1 1 1 1 1 1 1 1 1 1 1 1 1 1 1 1 1	USPAT;	2004/10/29 09:	L 5
	(mask\$4 or print\$4 or record\$4) and	US-PGPUB;		
	((circul\$6 or rotat\$5) same (stage\$1 or	EPO; JPO;	1	
	table\$1 or subtrate\$1 or wafer\$1 or	DERWENT		
	objet\$1))) and ((jet\$4 or eject\$4 or			
ļ .	discharg\$4) same (mask\$4 or print\$4 or			
	record\$4)) and ((circul\$6 or rotat\$5)			
	same (stage\$1 or table\$1 or subtrate\$1 or			
	wafer\$1 or objet\$1))) and ((jet\$4 or			
	eject\$4 or discharg\$4) same (mask\$4 or			
	print\$4 or record\$4) same (photosensitive			
	or photoresist))) and ((circul\$6 or			
	rotat\$5) with (stage\$1 or table\$1 or			
	subtrate\$1 or wafer\$1 or objet\$1))) not			
	((((((photoresist or photosensitive) and			
	(mask\$4 or print\$4 or record\$4) and			
	((circul\$6 or rotat\$5) same (stage\$1 or			
	table\$1 or subtrate\$1 or wafer\$1 or			
	objet\$1))) and ((jet\$4 or eject\$4 or			
	discharg\$4) same (mask\$4 or print\$4 or record\$4)) and ((circul\$6 or rotat\$5)			
	<pre>same (stage\$1 or table\$1 or subtrate\$1 or wafer\$1 or objet\$1))) and ((jet\$4 or</pre>			
	eject\$4 or discharg\$4) same (mask\$4 or			
	print\$4 or record\$4) same (photosensitive			
	or photoresist))) and ((circul\$6 or			
	rotat\$5) with (stage\$1 or table\$1 or			
	subtrate\$1 or wafer\$1 or objet\$1))) and			
	347/\$.ccls.)) not ((((((photoresist or			
	photosensitive) and (mask\$4 or print\$4 or			
	record\$4) and ((circul\$6 or rotat\$5) same			
	(stage\$1 or table\$1 or subtrate\$1 or			
	wafer\$1 or objet\$1))) and ((jet\$4 or	1		
	eject\$4 or discharg\$4) same (mask\$4 or			
	print\$4 or record\$4)) and ((circul\$6 or			
	rotat\$5) same (stage\$1 or table\$1 or			
	subtrate\$1 or wafer\$1 or objet\$1))) and	•	·	
	((jet\$4 or eject\$4 or discharg\$4) same			
	(mask\$4 or print\$4 or record\$4) same			
	(photosensitive or photoresist))) and			
	((circul\$6 or rotat\$5) with (stage\$1 or			
	table\$1 or subtrate\$1 or wafer\$1 or			
	objet\$1))) not (((((photoresist or			
	photosensitive) and (mask\$4 or print\$4 or		1	
	record\$4) and ((circul\$6 or rotat\$5) same			
	(stage\$1 or table\$1 or subtrate\$1 or			
	wafer\$1 or objet\$1))) and ((jet\$4 or	1		
	eject\$4 or discharg\$4) same (mask\$4 or			
	print\$4 or record\$4)) and ((circul\$6 or			
	rotat\$5) same (stage\$1 or table\$1 or			
	subtrate\$1 or wafer\$1 or objet\$1))) and			
	((jet\$4 or eject\$4 or discharg\$4) same			
	(mask\$4 or print\$4 or record\$4) same			
	(photosensitive or photoresist))) and			
	((circul\$6 or rotat\$5) with (stage\$1 or			
	table\$1 or subtrate\$1 or wafer\$1 or			
	objet\$1))) and 347/\$.ccls.)) and			
	((photoresist or photosensitive) adj			
	layer\$1))			
	objet\$1))) and 347/\$.ccls.)) and ((photoresist or photosensitive) adj			_

22	445	((((photoresist or photosensitive) and	USPAT;	2004/10/29	09.16
	113	(mask\$4 or print\$4 or record\$4) and	US-PGPUB;	2004/10/23	03.10
		((circul\$6 or rotat\$5) same (stage\$1 or	EPO; JPO;		
		table\$1 or subtrate\$1 or wafer\$1 or	DERWENT		
		objet\$1))) and ((jet\$4 or eject\$4 or	555		
1		discharg\$4) same (mask\$4 or print\$4 or			
		record\$4)) and ((circul\$6 or rotat\$5)			
		same (stage\$1 or table\$1 or subtrate\$1 or			
1		wafer\$1 or objet\$1))) and ((jet\$4 or			
		eject\$4 or discharg\$4) same (mask\$4 or			
		print\$4 or record\$4) same (photosensitive			
		or photoresist))) not ((((photoresist or			
		photosensitive) and (mask\$4 or print\$4 or			
		record\$4) and ((circul\$6 or rotat\$5) same			
		(stage\$1 or table\$1 or subtrate\$1 or			
		wafer\$1 or objet\$1))) and ((jet\$4 or			
		eject\$4 or discharg\$4) same (mask\$4 or			
		print\$4 or record\$4)) and ((circul\$6 or			
		rotat\$5) same (stage\$1 or table\$1 or			
		subtrate\$1 or wafer\$1 or objet\$1))) and			
		((jet\$4 or eject\$4 or discharg\$4) same			
		(mask\$4 or print\$4 or record\$4) same			
		(photosensitive or photoresist))) and			
		((circul\$6 or rotat\$5) with (stage\$1 or			
		table\$1 or subtrate\$1 or wafer\$1 or			
		objet\$1)))		<u> </u>	